١	Form.1A49.(Modified)	Atty Docket No.	Application No.:
		KLA1P015AD2/P611A2	Unknown
	Information Disclosure	Applicant:	10/623953
	Statement By Applicant	Lehman et al.	
		Filing Date	Group 2862
	(Use Several Sheets if Necessary)	Herewith	Nut Assigned

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Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.